



ABOUT E-BEAM PROCESSING SYSTEMS

Wasik Associates manufactures E-beam systems from 300 keV to 1 MeV. The Accelerator is the heart of the E-beam system. All other assemblies are supporting it. The Power Supply creates the voltage required by the accelerator. The Cable-Bushing Assembly is used to transmit this high voltage from the power supply to the accelerator. The Power Cabinet feeds the correct power into the power supply. The Control Cabinet maintains the desired beam while also monitoring all aspects of the system to insure safe, reliable operation. The Waveform Generator, along with the Scan Chamber, spreads out the electron beam making it useful as a processing tool. The Vacuum System maintains the required high vacuum to allow the free movement of electrons. Shielding safely stops all unused electrons and x-rays from escaping the processing chamber. The Security System insures that the shielding isn't disturbed during operation. Under-Beam Handling moves the product to be processed into the electron beam.

SYSTEM OPTIONS

We will design and manufacture a system to meet your requirements.